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To: Stephen Smart From: Gregory Muir
Fax: 511-273-8300 Pages: 17
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Re: 10/6/27.155 Date: 9/30/2005
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SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO. P102-US		SERIAL NO. 10/627,155			
		APPLICANT Patel, et al					
		FILING DATE 7/24/03		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	2003/0160540	8/28/03	Miller, et al.				
	6,819,470	11/16/04	Meier, et al.				
	2003/0117688	6/26/03	Meier, et al.				
	2003/0117686	6/26/03	DiCarlo				
	2002/0093721	7/18/02	Knipe				
	6,724,518	4/20/04	Meyer, et al.				
	6,147,790	11/14/00	Meier, et al.				
	6,285,490	9/4/01	Meier, et al.				
	6,523,961	2/25/03	Ilkov, et al.				
	2002/0024641	2/28/02	Ilkov, et al.				
	2004/0004753	1/8/04	Pan				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	WO 2004/001487	12/13/03	PCT			<input type="checkbox"/>	<input type="checkbox"/>
	WO 2004/000720	12/13/03	PCT			<input type="checkbox"/>	<input type="checkbox"/>
	WO 2004/001717	12/13/03	PCT			<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
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Filed 2/15/05

Attorney Docket No.: 38187-2594

SHEET 1 OF 1

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INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO.	SERIAL NO.				
		P102-US	10/627,155				
		APPLICANT Patel, et al					
SHEET 1 OF 1		FILING DATE 7/24/03	GROUP				
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	5,835,256	11/10/98	Huibers				
	6,046,840	04/04/00	Huibers				
	6,529,310	03/04/03	Huibers, et al.				
	6,396,619	05/28/02	Huibers, et al.				
	6,523,961	02/25/03	Ilkov, et al.				
	2003/0054588	03/20/03	Patel, et al.				
	2004/0125346	07/01/04	Huibers				
	2002/0132389	09/19/02	Patel, et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
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						<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
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Filed 6/14/04

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Filed 5/24/04

Attorney Docket No.: 38187-2594

PTO/SB/08A (10-01)

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U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

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Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1 of 6

Complete If Known

Application Number	10/627,155
Filing Date	7/24/03
First Named Inventor	Patel
Art. Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned
Attorney Docket Number	P102-US

U.S. PATENT DOCUMENTS

Examiner Initials	Cite No. ¹	Document Number Number - Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	/	US- 3,511,727	05-12-1970	Haya, R.G.	
		US- 4,190,488	02-26-1980	Winters, H.F.	
		US- 4,310,380	12-12-1982	Flamm et al.	
		US- 4,498,953	02-12-1985	Cook et al.	
		US- 6,051,503	04-18-2000	Bhardwaj, J.K.	
		US- 6,436,229	08-20-2002	Tai et al.	
		US- 6,162,367	12-19-2000	Tai et al.	
		US- 6,290,884 B1	09-18-2001	Patel et al.	
		US- 6,355,181 B1	03-12-2002	McQuarrie, A.D.	
		US- 2001/0002663 A1	06-07-2001	Tai et al.	
		US- 5,439,553	08-08-1995	Grant et al.	
		US- 2002/0032229 A1	03-21-2002	Leboultz et al.	
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		US- 5,726,480	03-10-1998	Pister, K.S.	
		US- 2002/0165899	12-12-2002	Reid	
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		US- 2003/0166342 A1	09/04/03	Chinn, et al.	

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Examiner Initials	Cite No. ¹	Foreign Patent Document Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		EP-0704884-A2	04-03-1996	Mehta, J.		
		EP-0822582-A2	02-04-1998	Bhardwaj, J.K.		
		EP-0822584-A2	04-04-1998	Bhardwaj, J.K.		
		WO-9949506	09-30-1999	McQuarrie, A.D.		
		EP-0878824-A2	11-18-1996	McQuarrie et al.		
		EP-0878824-A3	01-19-2000	McQuarrie et al.		
		JP-1982/57098679-A	06-18-1982	Tsunetschi, A.		
		JP-1983/58130529-A	08-04-1983	Yoshihiro et al.		
		JP-1985/60057938-A	04-03-1985	Katsumi et al.		
		WO-98/32163	07-23-1998	Tai et al.		

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Substitute for form 1449A/PTO				Complete if Known:	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/627,155
(use as many sheets as necessary)				Filing Date	7/24/03
				First Named Inventor	Patel
				Art Unit	Not Yet Assigned
				Examiner Name	Not Yet Assigned
Sheet	2	of	6	Attorney Docket Number	P102-US

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No. 1	Document Number Number- Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		US- 6,409,876 B1	06-25-2002	McQuarrie, et al.
		US- 6,396,619 B1	05-28-2002	Huibers, et al.
		US- 6,576,488 B2	08/10/03	Leung, et al.
		US- 6,238,581	05-29-2001	Hawkins, et al.
		US- 6,115,172	09-05-2000	Jeong
		US- 6,204,080	03-20-2001	Hwang
		US- 2003/0071015 A1	04/17/03	Chinn, et al.
		US- 2002/0164879 A1	11/07/02	Leung, et al.
		US- 2002/0183051 A1	11/07/02	Gopal, et al.
		US- 2003/0077878 A1	04/24/03	Kumar, et al.
		US- 6,197,810 B1	03/06/2001	Toda
		US- 6,500,358 B2	12/31/02	Goto, et al.
		US- 2003/0124848 A1	07/03/03	Chinn, et al.
		US- 2003/0219986 A1	11/27/03	Rattner, et al.
		US-		

FOREIGN PATENT DOCUMENTS				
Examiner Initials	Cite No. 1	Foreign Patent Document Country Code ³ -Number ⁴ - Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		JP-1997/09251981-A.	09-22-1997	Kazuaki et al.
		JP-1998/10313123-A	11-24-1998	Hannin et al.
		JP-1998/10317169-A	12-02-1998	McQuarrie et al.
		JP-1986/51187238-A	08-20-1986	Nobuo et al.
		JP-1988/61270830-A	12-01-1988	Toru, T.
		JP-1987/62071217-A	04-01-1987	Toru et al.
		JP-1988/63165713-A	08-28-1988	Tadashi, F.
		JP-1988/61053732-A	03-17-1988	Arata et al.
		JP-1988/61134019-A	08-21-1988	Shinji et al.
		JP-1988/61181131-A	08-13-1988	Shinji et al.

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/627,155
(use as many sheets as necessary)				Filing Date	7/24/03
				First Named Inventor	Patel
				Art Unit	Not Yet Assigned
				Examiner Name	Not Yet Assigned
Sheet	3	of	6	Attorney Docket Number	P102-US

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**INFORMATION DISCLOSURE
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Sheet

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Complete If Known

Application Number	10/627,155
Filing Date	7/24/03
First Named Inventor	Patel
Group Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned
Attorney Docket Number	P102-US

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. 1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T2
		ALIEV et al., "Development of Si(100) Surface Roughness at the Initial Stage of Etching in F2 and XeF2 Gases Ellipsometric Study", Surface Science 442 (1999), pp. 206-214.	
		GLIDEMEISTER, J.M., "Xenon Difluoride Etching System" (Nov. 17, 1997).	
		HABUKA et al., "Dominant Overall Chemical Reaction in a Chlorine Trifluoride-Silicon-Nitrogen System at Atmospheric Pressure", Japan Journal of Applied Physics Vol. 38 (1999), pp. 6466-6469.	
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		FLAMM et al., "XeF2 and F-Atom Reactions with Si: Their Significance for Plasma Etching", Solid State Technol. 26, 117 (1983).	
		IBBOTSON et al., "Plasmaless Dry Etching of Silicon with Fluorine-containing Compounds", J. Appl. Phys. Vol. 56 No. 10 (Nov. 1984), pp. 2938-2942.	
		IBBOTSON et al., "Comparison of XeF2 and F-atom Reactions with Si and SiO2", Applied Physics Letter, Vol. 44, 1129 (1984).	
		STRELLER et al., "Selectivity in Dry Etching of Si (100) and XeF2 and VUV Light", Elsevier Science B.V., Applied Surface Science Vol. 106 (1996), pp. 341-346.	
		VUGTS et al., "Si/XeF2 Etching: Temperature Dependence", J. Vac. Sci. Technol. A 14(5) (Sep/Oct 1996), pp. 2766-2774.	
		WINTERS, H.F., "Etch Products from the Reaction of XeF2 with SiO2, SiO3, Si3N4, SiC, and Si in the Presence of Ion Bombardment", J. Vac. Sci. Technol. B 1(4) (Oct/Dec 1983), pp. 927-931.	

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

5

of

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Application Number	10/627,155
Filing Date	7/24/03
First Named Inventor	Patel
Group Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned
Attorney Docket Number	P102-US

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.†	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T‡
		Kurt Willama, Etch Rates for Micromachining Processing-Part II, 2003 IEEE, Pgs 761-778, Journal of Microelectromechanical Systems, Vol. 12, No. 6, December 2003.	
		WINTERS et al., "The Etching of Silicon with XeF ₂ Vapor", Appl. Phys. Letter, Vol 34(1) (January 1, 1979), pp. 70-73.	
		XACTIX, Inc., Marketing Brochure (June 27, 1989).	
		"Xenon Difluoride Isotropic Etch System: Seeing Is Believing", Surface Technology Systems Ltd. brochure, Newport, UK (date unknown).	
		CHU et al., "Controlled Pulse-Etching with Xenon Difluoride", International Solid State Sensors and Actuators Conference (Transducers '97), Chicago, IL, Vol. 1 (June 16 - 19, 1997), pp. 665-668 (abstract only).	
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		CHAN et al., "Gas Phase Pulse Etching of Silicon for MEMS with Xenon Difluoride", Engineering Solutions for the Next Millennium: 1999 IEEE Canadian Conference on Electrical and Computer Engineering, Edmonton, Alberta, Vol. 3 (May 9 - 12, 1999), pp. 1837-1842 (abstract only).	
		CHANG et al., "Gas-Phase Silicon Micromachining with Silicon Difluoride", Proceedings of the SPIE - The International Society for Optical Engineering, Vol. 2841 (1995), pp. 117-128 (abstract only).	

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/627,156
				Filing Date	7/24/03
				First Named Inventor	Patal
				Group Art Unit	Not Yet Assigned
				Examiner Name	Not Yet Assigned
				Attorney Docket Number	P102-US
(use as many sheets as necessary)					
Sheet	8	of	8		

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